

Notice of References Cited	Application/Control No. 09/674,660		Applicant(s)/Patent Under Reexamination BHARDWAJ ET AL.	
	Examiner Alexis Wachtel		Art Unit 1764	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6841141	01-2005	Arno et al	423/490
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Saitiq et al; Plasmaless Cleaning Process of Silicone Surface Using Chlorine Trifluoride; 19 March 1990; Applied Physics Letters 56 (12); pp.1190-1121
	V	Ibbotson et al; Plasmaless Dry Etching of Silicon with Fluorine Containing Compounds; 15 November 1984; Applied Physics Letters 56 (10); pp.2939-2942
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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